

In the Specification:

Please replace the paragraph beginning at page 24, line 2, with the following paragraph:

C¹ -- According to one aspect of the present invention there is provided a piezoelectric device comprising a first element of porous crystalline material, a second element being attached to, or integrally formed with, the first element, and at least two electrodes being in electrical contact with the first element, such that subjecting the first element to an electric potential via the at least two electrodes results in a strain induced by the first element on the second element. --

[Please replace the paragraph beginning at page 24, line 9, with the following paragraph:]

-- According to another aspect of the present invention there is provided a method of producing a piezoelectric device comprising the steps of attaching to, or integrally forming with, a first element of porous crystalline material, a second element, and attaching to the first element at least two electrodes, such that subjecting the first element to an electric potential via the at least two electrodes results in a strain induced by the first element on the second element. --

Please replace the paragraph beginning at page 34, line 3, with the following paragraph:

C² -- Figure 5 shows a piezoelectric device in accordance with the teachings of the present invention, which is referred to hereinbelow as device 60. Device 60 includes a first element 62. Element 62 is of porous crystalline material, such as, but not limited to, porous silicon. Device 60 further includes a second element 64 which is attached to, or integrally formed with, first element 62. Device 60 further includes at least two electrodes 66 (three are shown) which is in electrical contact with first element 62. The arrangement of the above

C2 amended.

components is selected such that subjecting first element 62 to an electric potential via electrodes 66 results in a strain induced by first element 62 on second element 64. A method of producing a piezoelectric device according to the present invention is effected by attaching to, or integrally forming with, a first element 62 of porous crystalline material, a second element 64, and attaching to the first element (62) at least two electrodes 66, such that subjecting the first element 62 to an electric potential via the electrodes 66 results in a strain induced by the first element 62 on the second element 64. --

Please replace the paragraph beginning at page 37, line 1, with the following paragraph:

C3

-- According to a presently preferred embodiment of the present invention, and as is further shown in Figure 7, adaptive reflector 80 further includes at least two electrodes 88, through which an electric potential is applicable to first layer 82. According to an alternative embodiment, adaptive reflector 80 further includes at least one light source 89 with which light is applicable to first layer 82. --

In the Claims:

Please amend claims 1 and 29 as follows:

C4

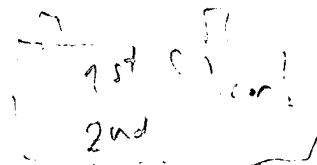
1. (Amended) A piezoelectric device comprising a first element of porous crystalline silicon, a second element being attached to, or integrally formed with, said first element, and at least two electrodes being in electrical contact solely with said first element of said first and second elements, such that subjecting said first element to an electric potential via said at least two electrodes results in a strain induced by said first element on said second element.

1.15 PEC

SiC Catalyst

DELL

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SiN